Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 220471US2S		SERIAL NO. 10/091,423	
LIST O	REPE	RENCES CITED BY AI	PPLICANT	Yusuke KAWAGUCHI, et al.			
1 7		)		FILING DATE		GROUP	
MAR 0 2 2004		1		March 7, 2002		2826	
MAR 0 2 2004 B March 7, 2002 2826 U.S. PATENT DOCUMENTS							
ELAMINDER		DOCUMENT	DATE	NAME	CLASS	SUB	FILING DATE
INITIAL		NUMBER		INAIVIE	CDASS	CLASS	IF APPROPRIATE
PE	AA	4,941,026	07/10/90	TEMPLE	<b>.</b>		
Po	AB	5,637,898	06/10/97	BALIGA			
Po	AC	5,679,966	10/21/97	BALIGA ET AL.			
PB	AD	5,844,273	12/01/98	KONISHI			
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FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY		TRANSLATION YES NO	
	AO	EP 0 238 749 A2	09/30/87	EUROPEAN			
	AP					-	
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	AT						
	AU						
	AV						
		OTUGE DE					
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
R	AW	BALIGA, B. J., "Critical Nature of Oxide/Interface Quality for SiC Power Devices", 9 <sup>th</sup> Biennial Conference on Insulating Films on Semiconductors, Villard De Lans, France, 7-10 June 1995, Microelectronic Engineering, June 1995, Elsevier Publishers B.V., Amsterdam, Netherlands, vol. 28, no. 1-4, pages 177-184.					
	AX						
	AY				<u>-</u>		
	AZ				Addit	ional Refer	ences sheet(s) attached
Examiner CIII Row tru				pts	Date Considered or 12 4 (of		
*Examiner: Initial if perence is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							
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